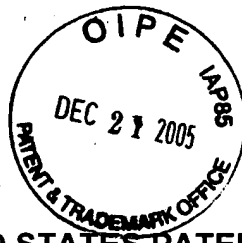


Docket No. EATNP147US

02-IMP-056



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re **PATENT** application of:

Applicant: Peter Kellerman et al.  
Application No.: 10/642,939  
For: MEMS Based Multi-Polar Electrostatic Chuck  
Filing Date: August 18, 2003  
Examiner: Ann Thi Hoang  
Art Unit: 2836

**REPLY TO OFFICE ACTION DATED OCTOBER 6, 2005**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Favorable reconsideration of the above-identified application is respectfully requested in view of the following remarks.